

gas while controlling the temperature of the specimen below 200°C;

a rinsing unit that can perform rinsing with a liquid of an exposed surface by the etching of the lamination layer including the NiFe or NiFeCo alloy, so as to wash out substantial corrosive elements on the exposed surface, immediately after the etching; and

a dryer unit that can perform drying of the rinsed surface of the lamination layer including the NiFe or NiFeCo alloy immediately after the rinsing thereof, wherein said etching process unit can further perform in succession etching of the dried surface of the lamination layer including the NiFe or NiFeCo alloy with a high density gas plasma of a low ion energy while controlling the temperature of the specimen below 200 °C.

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cwt

2. (twice amended) An apparatus for processing a specimen according to claim 1, further comprising:

an atmospheric loader of the specimen laminated on the substrate; a vacuum transport unit having a vacuum transport robot therein; and unload and load lock chambers connecting between said atmospheric loader and said vacuum transport unit for delivering the specimen via an atmospheric transport unit, wherein

said vacuum transport unit is connected to an etching process chamber of said etching process unit, and

said atmospheric loader is connected via said atmospheric transport unit to at least a rinsing cup and hot plate provided in said rinsing and dryer units.